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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10009521	FILING DATE 12/11/2001	CLASS 173.26	SUBCLASS 655	GAUD 655	EXAMINER VALENTINE
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****APPLICANTS:** Izuo Shinichi; Ohji Hiroshi; Tsutsumi Kazuhiko; French Patrick;****CONTINUING DATA VERIFIED:**

THIS APPLICATION IS A 371 OF PCT/JP00/03307 05/24/2000

**** FOREIGN APPLICATIONS VERIFIED:**

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PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	
Foreign priority claimed	<input type="checkbox"/> yes <input type="checkbox"/> no	ATTORNEY DOCKET NO	
35 USC 119 conditions met	<input type="checkbox"/> yes <input type="checkbox"/> no	401479	
Verified and Acknowledged Examiners's initials			
TITLE : Method and apparatus for radiation assisted electrochemical etching and etched product			

U.S. DEPT. OF COMM. / PAT. & TM. PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Assistant Examiner	Total Claims
			Print Claim for O.G.
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drawg.	Fig. Drawg.
		Print Fig.	
		Primary Examiner	
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner
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